

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO.: 8733.6836		SERIAL NO.: 09/170,625	
LIST OF REFERENCES CITED BY APPLICANT (Use Several Sheets if Necessary)				APPLICANT: Duck Hyun CHOI			
				FILING DATE: October 13, 1998		GROUP: 2823	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
G	AA	4,309,225	01/1982	FAN et al.	148	1.5	
G	AB	4,626,448	12/1986	HAYS	427	39	
G	AC	5,364,664	11/1994	TSUBOUCHI et al.	427	535	
G	AD	5,492,843	02/1996	ADACHI et al.	437	21	
G	AE	5,576,222	11/1996	ARAI et al.	437	4	
G	AF	5,619,044	04/1997	MAKITA et al.	257	64	
G	AG	5,639,698	06/1997	YAMAZAKI et al.	437	228	
G	AH	5,663,077	09/1997	ADACHI et al.	438	151	
G	AI	5,677,240	10/1997	MURIKAMI et al.	437	195	
G	AJ	5,985,741	11/1999	YAMAZAKI et al.	438	486	
G	AK	6,066,547	05/2000	MAEKAWA	438	486	
	AL						
	AM						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
G	AN	21-40915	05/1990	JP (Japan)	Abstract		
G	AO	80-06053	01/1996	JP (Japan)	Abstract		
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
G	AP	Y. Kawazu, et al., "Low-Temperature Crystallization of Hydrogenated Amorphous Silicon Induced by Nickel Silicide Formation", Japanese Journal of Applied Phys., Vol. 29, No. 12, December 1990, pp. 2698-2704					
	AQ						
	AR						
	AS						
EXAMINER: <i>F. J. R. S. N.</i>				DATE CONSIDERED: <i>Oct 13 2000</i>			
<p>*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP-609;          Draw line through citation if not in conformance and not considered. Include copy of this form with next          communication to applicant.</p>							